

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Yong-Pil Han et al.

Serial No.: 09/498,303

Filed: February 4, 2000

For: HF Vapor Phase Wafer Cleaning and Oxide Etching

Confirmation No. 8629

Group Art Unit: 1763

Examiner: T. Dang

COMMISSIONER FOR PATENTS

P. O. BOX 1450

ALEXANDRIA, VIRGINIA 22313-1450

I hereby certify that this correspondence is being deposited on the date shown below with the United States Postal Service with sufficient postage as first class mail, under 37 CFR 1.8(a), in an envelope addressed to: Commissioner For Patents, Alexandria, VA 22313-1450

Theresa A. Lober
November 20, 2003

PETITION FOR THREE -MONTH EXTENSION OF TIME UNDER 37 C.F.R. 1.136(a)

Hereby is petitioned the Assistant Commissioner for Patents to extend for the patent application referenced above the period for response to the Examiner's Action mailed May 21, 2003, for three (3) months, extending the last day of the response period from August 21, 2003, up to and including November 21, 2003.

A response to the Examiner's Action is being filed on even date herewith.

Please apply the extension fee of \$475.00 under 1.17(a)(3) to Deposit Account No. 19-2553. Please apply any deficiency in the stated fee and any other required fees, and please apply any overpayment, to Deposit Account No. 19-2553.

Respectfully submitted,

Date

Nov. 20, 2003

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